IN THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the application.

1. (Currently Amended) A fabrication method of a light-emitting device comprising the steps of:

ejecting a first solution containing a carrier injection material or a carrier transporting material ~~a light-emitting body composition~~ from a below toward an anode or a cathode facing downward under a pressure lower than atmosphere pressure; ~~and~~

forming a first thin film ~~having at least one layer structuring a light-emitting body~~ by depositing the carrier injection material or the carrier transporting material ~~the light-emitting body composition~~ on the anode or the cathode;

ejecting a second solution containing a luminescent material from the below toward the anode or the cathode facing downward under a pressure lower than atmosphere pressure; and

forming a second thin film by depositing the luminescent material on the first thin film.

2. (Currently Amended) A fabrication method of a light-emitting device comprising the steps of:

ejecting a first solution containing a carrier injection material or a carrier transporting material ~~a light-emitting body composition~~ from a below toward an anode or a cathode facing downward under a pressure of 1×10^2 to 1×10^5 Pa; ~~and~~

forming a first thin film ~~having at least one layer structuring a light-emitting body~~ by depositing the carrier injection material or the carrier transporting material ~~the light-emitting body composition~~ on the anode or the cathode;

ejecting a second solution containing a luminescent material from the below toward the anode or the cathode facing downward under a pressure of 1×10^2 to 1×10^5 Pa; and

forming a second thin film by depositing the luminescent material on the first thin film.

3. (Currently Amended) A fabrication method of a light-emitting device comprising the steps of:

ejecting a first solution containing a carrier injection material or a carrier transporting material ~~a light-emitting body composition~~ from a below toward an anode or a cathode facing downward under a pressure lower than atmosphere pressure; and

forming a first thin film ~~having at least one layer structuring a light-emitting body~~ by depositing a remaining of the the carrier injection material or the carrier transporting material ~~the light-emitting body composition~~ on the anode or the cathode and volatilizing a first solvent in the first solution in a first duration before the first solution arrives at the anode or the cathode;

ejecting a second solution containing a luminescent material from the below toward the anode or the cathode facing downward under a pressure lower than atmosphere pressure; and

forming a second thin film by depositing the luminescent material on the first thin film and volatilizing a second solvent in the second solution in a second duration before the second solution arrives at the first thin film.

4-30. (Canceled)

31. (New) A fabrication method of a light-emitting device according to claim 1,

wherein under the pressure lower than atmosphere pressure is in an inert gas atmosphere at 1

$\times 10^3$ to 1×10^5 Pa.

32. (New) A fabrication method of a light-emitting device according to claim 2,

wherein under the pressure lower than atmosphere pressure is in an inert gas atmosphere at 1 $\times 10^3$ to 1×10^5 Pa.

33. (New) A fabrication method of a light-emitting device according to claim 3,

wherein under the pressure lower than atmosphere pressure is in an inert gas atmosphere at 1 $\times 10^3$ to 1×10^5 Pa.

34. (New) A fabrication method of a light-emitting device according to claim 1,

wherein the first thin film is formed in a first deposition chamber of a multi chamber,

wherein the second thin film is formed in a second deposition chamber of the multi chamber,

wherein the first thin film and the second thin film are formed in the multi chamber without exposure of the first thin film and the second thin film in air, and

wherein the first deposition chamber and the second deposition chamber each includes heads of solution-applying device.

35. (New) A fabrication method of a light-emitting device according to claim 2,

wherein the first thin film is formed in a first deposition chamber of a multi chamber,

wherein the second thin film is formed in a second deposition chamber of the multi chamber,

wherein the first thin film and the second thin film are formed in the multi chamber without exposure of the first thin film and the second thin film in air, and

wherein the first deposition chamber and the second deposition chamber each includes heads of solution-applying device.

36. (New) A fabrication method of a light-emitting device according to claim 3,

wherein the first thin film is formed in a first deposition chamber of a multi chamber,

wherein the second thin film is formed in a second deposition chamber of the multi chamber,

wherein the first thin film and the second thin film are formed in the multi chamber without exposure of the first thin film and the second thin film in air, and

wherein the first deposition chamber and the second deposition chamber each includes heads of solution-applying device.

37. (New) A fabrication method of a light-emitting device according to claim 1,

wherein the anode or the cathode is set up in a range of 0° to 30° relative to a horizontal plane.

38. (New) A fabrication method of a light-emitting device according to claim 2,

wherein the anode or the cathode is set up in a range of 0° to 30° relative to a horizontal plane.

39. (New) A fabrication method of a light-emitting device according to claim 3,

wherein the anode or the cathode is set up in a range of 0° to 30° relative to a horizontal plane.